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CENTRAL FAX CENTER****BEST AVAILABLE COPY****OCT 30 2006**Docket No. 740756-2713
Application No. 10/774,432
Page 8**REMARKS**

The above amendment with the following remarks is submitted to be fully responsive to the Office Action of August 2, 2006. Reconsideration of this application in light of the amendment and the allowance of this application are respectfully requested.

Claims 17-34 were pending in the present application prior to the above amendment. In response to the Office Action, claims 21, 27, 31, and 34 are amended, and new claims 35-42 are added. Therefore, claims 17-42 are pending in the present application and are believed to be in proper condition for allowance.

Initially, the Applicants acknowledge with appreciation, the Examiner's indication of allowable subject matter in claims 17-20, 23-26, 29, 30, 32, and 33, and in claims 31 and 34 if rewritten in independent form to include all the limitations of the base claim and any intervening claims.

Referring now to the Office Action, claims 21-22 and 27-28 are rejected under 35 U.S.C. 103(a) as being unpatentable over Yamazaki et al. (US Pub. 2002/0024051; hereinafter "Yamazaki") in view of Takacs et al. (US Pat. 6,244,212; hereinafter "Takacs"). Insofar as this rejection applies to the amended claims, Applicants respectfully traverse.

As amended, claim 21 recites a method for manufacturing a semiconductor device by depositing a film over a substrate moving an evaporation source including first and second crucibles in the X direction while moving the substrate in the Y direction, where each of the first and second crucibles includes a shutter. As amended, claim 27 recites a method for manufacturing a semiconductor device by depositing an EL material over a substrate by moving an evaporation source in the X direction while moving the substrate in the Y direction, where each of the first and second crucibles includes a shutter. Support for the amendments is found throughout the original specification, including, e.g., p. 8, ln. 29 - p. 9, ln. 11.

The Examiner contends that Yamazaki in combination with Takacs teaches a method for manufacturing a semiconductor device of depositing a film or EL layer over a substrate and reciprocating an evaporator in one direction while moving the substrate in another direction. However, Yamazaki in combination with Takacs does not teach or suggest a method with two crucibles in the X direction, where each of the first and second crucibles includes a shutter, as recited in amended claims 21 and 27. In light of the amendments, it is

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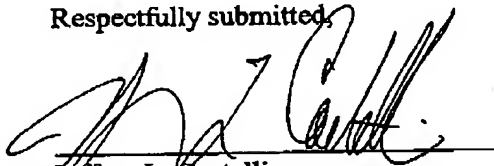
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respectfully submitted that claims 21-22 and 27-28 are not anticipated or rendered obvious by Yamazaki in view of Takacs.

In view of the foregoing, it is submitted that the present application is in condition for allowance and a notice to that effect is respectfully requested. However, if any issue remains after considering this response, the Examiner is invited to call the undersigned to expedite the prosecution and work out any such issue by telephone.

Respectfully submitted,


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